

# WaferMate300™

## Robotic Wafer Handling

### High Performance Wafer-Handling Platform

The WaferMate300 is a highly configurable, BOLTS-compatible robotic wafer-handling cell that mates high performance with cost competitiveness. As an ISO Class-2 clean FEOL EFEM, this platform includes all applicable mini-environment components, E84 compliance and rear hand-off.

### FEATURES AND BENEFITS

- Pairs with all types of process tools and environments.
- Super reliable, absolute encoder, 4-axis robots.
- Can service up to 3 process tools.
- 300mm automation platform, adaptable for 200mm and smaller substrates.
- Robots fitted with range of end effector technologies, including vacuum, Bernoulli, edge grip and more.
- Full safety guarding (OSHA and ANSI compliant).



### STANDARD ACCESSORIES

- FOUP Opener
- SMIF Pod Opener
- Aligner
- OCR
- Barcode
- Ionization Bars
- Mini Environment
- Wafer Flip Module
- DEK Compatible Transfer Station
- Wafer Conveyor/Oven Interface
- SMEMA & SECS/GEM Interfaces

### TECHNICAL SPECS

Footprint	991"W x 1041"L x 2063"T
Wafer Alignment	to ± .05°
Wafer Placement	±100µm
Clean Room Classification	Up to ISO Class 2 (Optional)
Wafer Interface Options	SMEMA Transfer Station SECS/GEM Wafer Conveyor
Loadport Positions Available	1 or 2

MTBF	60,000 hours
Full SEMI Compliance	
SEMI S2, S5, CE Compliant	
Uptime	>97%
Handling Capabilities	Thin Wafers Bonded Wafers Warped Wafers Perforated Wafers Thick Wafers Trenched Wafers Glass Wafers

For additional information, visit [jabil.com/precision-automation](http://jabil.com/precision-automation)